

Patent
Attorney's Docket No. 001425-108

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Ge XU et al.

Application No.: 09/863,338

Filed: May 24, 2001

For: CVD APPARATUS

) **HAND-DELIVERY**
) **CP 3 - 8TH FLOOR**
)
) Group Art Unit: 1763
)
) Examiner: S. MacArthur
)
) Confirmation No. 1018
)

#6A
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ml

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Preliminary to examination, kindly enter new claims 25-31 as follows.

20
25 (new) A CVD apparatus as stated in claim 1, further comprising an RF power supply for feeding a cleaning RF power and a switch for connecting the partitioning wall section to the RF power supply with suitable timing so as to produce a cleaning plasma in the film deposition process space.

A
B
26 (new) A CVD apparatus as stated in claim 5, wherein the connecting means includes a switch which selectively connects the partitioning wall to the RF power supply for feeding a cleaning RF power and to a ground for cleaning using the RF power supplied to the radio-frequency electrode in the first chamber.